

Search Notes

Application/Control No.

10/825,110

Examiner

John Rivell

Applicant(s)/Patent under
Reexamination

CHEN, MEI-LI

Art Unit

3753

SEARCHED

Class	Subclass	Date	Examiner
137	625.17 625.4 625.41	7/13/2006	
251	313	7/13/2006	

INTERFERENCE SEARCHED

Class	Subclass	Date	Examiner
Interference Search History Printout		7/13/2000	

**SEARCH NOTES
(INCLUDING SEARCH STRATEGY)**

	DATE	EXMR
EAST Search History Printout	7/13/2006	